

PATENT 3887-0114P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant:

KIM, Kyong-Min et al.

Conf.:

Appl. No.:

New

Group:

Filed:

June 12, 2002

Examiner:

For:

METHOD FOR FABRICATING CAPACITOR OF

SEMICONDUCTOR MEMORY DEVICE

LETTER

Assistant Commissioner for Patents Washington, DC 20231

June 12, 2002

Sir:

Under the provisions of 35 U.S.C. § 119 and 37 C.F.R. § 1.55(a), the applicant(s) hereby claim(s) the right of priority based on the following application(s):

Country

Application No.

Filed

KOREA

2001-32686

June 12, 2001

A certified copy of the above-noted application(s) is(are) attached hereto.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fee required under 37 C.F.R. §§ 1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By Joseph A. Kolasch, #22,463

P.O. Box 747

JAK/cqc 3887-0114P Falls Church, VA 22040-0747

(703) 205-8000

Attachment